



IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE

Applicant: Hyug-Jin Kwon

Serial No.: 10/615,062

Filed: July 8, 2003

Title: BATCH TYPE ATOMIC  
LAYER DEPOSITION  
APPARATUS AND IN-SITU  
CLEANING METHOD THEREOF

Group Art Unit: 1763

Examiner: S. MacArthur

I hereby certify that this paper (or fee) is being deposited with the United States Postal Service, first class postage prepaid, addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450

March 30, 2006

  
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James P. Zeller  
Reg. No. 28,491

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The documents listed on the enclosed Form PTO-1449 are identified pursuant to 37 CFR §§ 1.56, 1.97, and 1.98. Copies of the documents are enclosed as required.

The documents are related to Chen et al. U.S. Patent Application Publication No. 2003/0121608, which was cited in the official action dated December 30, 2005.

Relevant portions of the listed documents include Figures 1, 3, 4, and 7, which are the same in each document.

No item of information contained in the information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application, and, to the knowledge of the person signing the certification after making reasonable inquiry, no item of information contained in the information disclosure statement was known to any individual designated in § 1.56(c) more than three months prior to the filing of the information disclosure statement.

Entry and consideration of the submitted documents are solicited.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP

March 30, 2006

By:

  
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Form O-1449 (Modified)

U.S. Department of Commerce  
Patent and Trademark OfficeAtty. Docket No.  
29926/39496Serial No.  
10/615,062**INFORMATION DISCLOSURE STATEMENT**Applicant  
Hyug-Jin Kwon.Filing Date  
July 8, 2003Group  
1763**U.S. PATENT DOCUMENTS**

*Examiner Initials	Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate
	6,916,398	07/12/05	Chen et al.	156	345.33	12/21/2001
	2003/0079686	05/01/03	Chen et al.	118	715	12/21/2001

**FOREIGN PATENT DOCUMENTS**

*Examiner Initials	Document Number	Publication Date	Country	Class	Subclass	Translation	
						Yes	No

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)**


Examiner	Date Considered
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	